

Introduction and Acknowledgments  
MASTER MODULE 6

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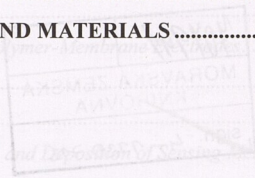
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## MASTER MODULE 6

# CHEMICAL SENSORS AND BIOSENSORS

ver.1.5

Edited by Gillian McMahon

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## MAGNETIC SENSORS

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Magnetic sensors are used in applications everywhere: from home appliances to cars, industry and scientific instruments. They either sense magnetic field itself, or more often, another physical variable which is transformed into a magnetic response. Magnetic sensors are reliable, they have a large operating temperature range and they are resistant to vibrations, dirt and interference. More detailed information on magnetic sensors can be found in general sensor books [1-3] and in specialised literature [4-6].

## MASTER MODULE 11

### NEW TECHNOLOGIES AND MATERIALS

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# MASTER MODULE 7

## LEVEL, POSITION AND DISTANCE

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## MASTER MODULE 8

### TEMPERATURE SENSORS

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Production: L.Indesteege, VIA, Belgium

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## MASTER MODULE 9

# SOLID-STATE GYROSCOPES AND NAVIGATION

Written by Dr André Migeon and Dr Anne-Elisabeth Lenel, M2A Technologies Sarl (France)

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